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DATE MAILED: 12/20/2004

| APPLICATION NO. | FILING DATE | FIRST NAMED INVENTOR | ATTORNEY DOCKET NO. | CONFIRMATION NO. |
|--|-----------------|----------------------|---------------------|------------------|
| 10/624,540 | 07/23/2003 | Yoshinari Ichihashi | 57810-070 | 7515 |
| 20277 | 7590 12/20/2004 | | EXAMINER | |
| 1,10,2,10,10 | TT WILL & EMERY | TRAN, MINH LOAN | | |
| 600 13TH STREET, N.W. WASHINGTON, DC 20005-3096 | | | ART UNIT | PAPER NUMBER |
| | , | | 2826 | |

Please find below and/or attached an Office communication concerning this application or proceeding.

| | | Application No. | Applicant(s) | | | | |
|---|---|--|--|--------|--|--|--|
| | | 10/624,540 | ICHIHASHI ET AL. | | | | |
| Office A | Action Summary | Examiner | Art Unit | | | | |
| • | | Minh-Loan T. Tran | 2826 | | | | |
| The MAILIN | IG DATE of this communication | n appears on the cover sheet v | vith the correspondence address - | , | | | |
| A SHORTENED S THE MAILING DA - Extensions of time may after SIX (6) MONTHS - If the period for reply is - Failure to reply within the Any reply received by the | TATUTORY PERIOD FOR R TE OF THIS COMMUNICATION be available under the provisions of 37 Confrom the mailing date of this communication ecified above is less than thirty (30) days, specified above, the maximum statutory properties are extended period for reply will, by the Office later than three months after the listment. See 37 CFR 1.704(b). | ON. FR 1.136(a). In no event, however, may a sin. a reply within the statutory minimum of the eriod will apply and will expire SIX (6) MO statute, cause the application to become A | reply be timely filed irty (30) days will be considered timely. NTHS from the mailing date of this communications. BANDONED (35 U.S.C. § 133). | ation. | | | |
| Status | | | | | | | |
| 1) Responsive | to communication(s) filed on | <u>23 July 2003</u> . | | | | | |
| 2a)☐ This action is | | This action is non-final. | | | | | |
| • | | | | | | | |
| Disposition of Claims | S | | | | | | |
| 4a) Of the ab 5) | | ndrawn from consideration. | | | | | |
| Application Papers | | | | | | | |
| 9)☐ The specifica | ition is objected to by the Exa | miner. | | | | | |
| 10) The drawing | 10) The drawing(s) filed on is/are: a) accepted or b) objected to by the Examiner. | | | | | | |
| Applicant may | not request that any objection to | o the drawing(s) be held in abeya | ince. See 37 CFR 1.85(a). | | | | |
| <u> </u> | * ', ' | * | g(s) is objected to. See 37 CFR 1.12 ed Office Action or form PTO-152 | • • | | | |
| Priority under 35 U.S | .C. § 119 | | | | | | |
| a)⊠ All b)□ a 1.□ Certifi 2.⊠ Certifi 3.□ Copies applic | nent is made of a claim for for Some * c) None of: ed copies of the priority docured copies of the priority docures of the certified copies of the ation from the International Burned detailed Office action for a | ments have been received. ments have been received in a priority documents have been ureau (PCT Rule 17.2(a)). | Application No. <u>09/788,673</u> . n received in this National Stage | | | | |
| Attachment(s) | | | | | | | |
| 1) Notice of References | Cited (PTO-892) | | Summary (PTO-413) (s)/Mail Date | | | | |
| | n's Patent Drawing Review (PTO-948 e Statement(s) (PTO-1449 or PTO/S e <u>7/23/03</u> . | | Informal Patent Application (PTO-152) | | | | |

Application/Control Number: 10/624,540

Art Unit: 2826

DETAILED ACTION

Priority

Acknowledgment is made of applicant's claim for foreign priority under 35
 U.S.C. 119(a)-(d). The certified copy has been filed in parent Application No.
 09/788,673, filed on 02/21/2001.

Information Disclosure Statement

- 2. The information disclosure statement filed 07/23/2003 has been considered.
- 3. The Preliminary Amendment filed on 07/23/2003 has been entered.

Oath/Declaration

4. The Oath/Declaration filed on 07/23/2003 is acceptable.

Claim Rejections - 35 USC § 102

5. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

(b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.

Claims 8-15, 17-19 are rejected under 35 U.S.C. 102(b) as being anticipated by Gocho, Tetsuo (JP 08-250,449).

With regard to claim 17, figure 2 of Gocho, Tetsuo discloses a method of fabricating a semiconductor device comprising the steps of forming an insulator film including a phosphorus silicate glass (PSG) upper insulator film 17 and a SiN lower insulation film 16 on a first conductive part 57 (or 56, 53); etching the insulator film thereby forming an opening 63 (or 62, 61) reaching the first conductive part 57 (or 56,

Application/Control Number: 10/624,540

the transistor can be formed.

Art Unit: 2826

53); wherein the etching is conducted under substantially the same condition with respect to the upper insulator film 17 and the lower insulator film 16. Figure 2 of Gocho, Tetsuo does not show a second conductive part connected to the first conductive part 57 (or 56, 53) through the opening 63 (or 62, 61). It is inherent that the second conductive part connected to the first conductive part 57 (or 56, 53) through the opening 63 (or 62, 61) so that the source electrode, the drain electrode and the gate electrode of

With regard to claims 18,19, 12, 13, 15, figure 2 and paragraph [0026]-[0028], [0030], and [0019] of Gocho, Tetsuo disclose the etching is conducted under a condition where a C-F based polymer (C_4F_8) is formed when the first conductive part 57 (or 56, 53) is exposed to the etching.

With regard to claim 8, it is inherent that the lower SiN insulator film 16 has a higher etching selection ratio than the upper phosphorus silicate glass (PSG) insulator film 17 because the SiN insulator film 16 functions as an etch stopper (note paragraph [0021] of Gocho, Tetsuo.)

With regard to claim 9, figure 2 and paragraph [0013] of Gocho, Tetsuo disclose the first conductive part 57 (or 56, 53) contains a material having a higher etching selection ratio than the lower SiN conductive insulator 16.

With regard to claim 10, figure 2(1) of Gocho, Tetsuo discloses a step of silicifying the first conductive part 57 (or 56, 53) for forming silicide region 59 (or 58, 55) in advance of the step of forming the insulator film (16, 17).

Application/Control Number: 10/624,540

Art Unit: 2826

With regard to claim 11, figure 2 (1-4) of Gocho, Tetsuo discloses the first conductive part include a gate electrode 53, a source region 56 and a drain region 57; and the step of silicifying the first conductive part includes a step of silicifying the surfaces of the gate electrode 53, the source region 56 and the drain region 57 in order to form the silicide regions 55 (gate), 58 (source) and 59 (drain).

With regard to claim 14, figure 2 of Gocho, Tetsuo discloses the SiN lower insulator film 16 is formed to be in contact with the surface of the first conductive part 57 (or 56, 53).

Claim Rejections - 35 USC § 103

- 6. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claim 16 is rejected under 35 U.S.C. 103(a) as being unpatentable over Gocho, Tetsuo (JP 08-250,449).

Gocho, Tetsuo does not disclose the lower insulator includes an SOG film.

Although Gocho, Tetsuo does not teach exact the material of the lower insulator film as that claimed by applicant, the material differences are considered obvious design choices and are not patentable unless unobvious or unexpected results are obtained from these changes. It appears that these changes produce no functional differences and therefore would have been obvious. Note *In re* Leshin, 125 USPQ 416, *In re Woodruff*, 919 F.2d 1575, 1578, 16 USPQ2d 1934, 1936 (Fed. Circ. 1990).

Page 5

Application/Control Number: 10/624,540

Art Unit: 2826

Conclusion

7. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Minh-Loan T. Tran whose telephone number is (571) 272-1922. The examiner can normally be reached on Monday-Friday 9:00 AM-5:30 PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Nathan J. Flynn can be reached on (571) 272-1915. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Mlt 12/04 Minh-Loan T. Tran Primary Examiner

double Em

Art Unit 2826